Claims

I claim:

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A method of manufacturing an integrated circuit device that comprises an insulation layer, the method comprising:

exposing at least a portion of an insulation layer that comprises oxygen to a metal precursor that is reactive with oxygen so as to form a first metal oxide layer on the at least a portion of the insulation layer.

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2. The method of Claim 1, wherein exposing the at least a portion of the insulation layer that comprises oxygen to the metal precursor comprises:

pulsing the metal precursor over the integrated circuit device; and exposing the integrated circuit device to an inert gas.

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3. The method of Claim 2, wherein pulsing the metal precursor is performed for a duration of about 0.1 to 2 seconds and at a flow rate of about 50 to 300 sccm.

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4. The method of Claim 2, wherein exposing the integrated circuit device to an inert gas is performed for a duration of about 0.1 to 10 seconds and at a flow rate of about 50 to 300 sccm.

5. The method of Claim 2, wherein pulsing the metal precursor comprises:

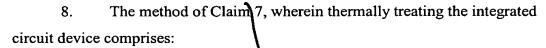
pulsing the metal precursor and a carrier gas over the integrated circuit device.

- 6. The method of Claim 5, wherein the carrier gas is argon.
- 7. The method of Claim 2, further comprising:

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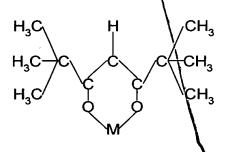
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thermally treating the integrated circuit device in an oxygen atmosphere using one of a rapid thermal processing apparatus and a furnace type thermal processing apparatus.



thermally treating the integrated circuit device in the oxygen atmosphere using a rapid thermal processing apparatus at a temperature of about 400 to 600°C for a duration of about 10 seconds to 10 minutes.

9. The method of Claim 1, wherein the metal precursor comprises a gas selected from the group of gases consisting of TriMethyl Aluminum (TMA), DiMethylAluminum Hydride (DMAH), DiMethylEthylAmine Alane (DMEAA), TriIsoButylAluminum (TIBA), TriEthyl Aluminum (TEA), TaCl₅, Ta(OC₂H₅)₄,TiCl₄, Ti(OC₂H₅)₄, ZrCl₄, HfCl₄, Nb(OC₂H₅)₅, Mg(thd)₂, Ce(thd)₃, and Y(thd)₃, wherein thd is given by the following structural formula:



- The method of Claim 1, wherein exposing the at least a portion of the insulation layer that comprises oxygen to the metal precursor is performed at a temperature of about 100 to 400°C and at a pressure of about 0.1 to 1 torr.
- 11. The method of Claim 1, wherein the insulation layer comprises a capacitor dielectric layer.
- 12. The method of Claim 1, wherein the insulation layer comprises a material selected from the group of materials consisting of: TiO₂, SiO₂, Ta₂O₅, Al₂O₃, BaTiO₃, SrTiO₃, (Ba, Sr)TiO₃, Bi₄Ti₃O₁₂, PbTiO₃, PZT((Pb, La)(Zr, Ti)O₃), and (SrBi₂Ta₂O₉)(SBT).
 - 13. The method of Claim 1, further comprising:

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encapsulating the first metal oxide layer and the insulation layer in a second metal oxide layer.



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14. An integrated circuit device, comprising:

a capacitor that comprises a lower electrode layer, a dielectric layer on the lower electrode layer, and an upper electrode layer on the dielectric layer;

a first metal oxide layer that is disposed on an exposed portion of the dielectric layer and has a first density associated therewith; and

a second metal oxide layer that encapsulates the capacitor and the first metal oxide layer and has a second density associated therewith that is greater than the first density.

- 15. The integrated circuit device of Claim 14, wherein the first and second metal oxide layers each comprise an element selected from the group of elements consisting of: Al, Ta, Ti, Zr, Mg, Ce/Y, Nb, Hf, Sr, and Ca.
- 16. The integrated circuit device of Claim 14, wherein the dielectric layer comprises a material selected from the group of materials consisting of: TiO₂, SiO₂, Ta₂O₅, Al₂O₃, BaTiO₃, SrTiO₃, (Ba, Sr)TiO₃, Bi₄Ti₃O₁₂, PbTiO₃, PZT((Pb, La)(Zr, Ti)O₃), and (SrBi₂Ta₂O₉)(SBT).
- 17. The integrated circuit device of Claim 14, wherein the first metal oxide layer is disposed on a sidewall of the dielectric layer and a portion of a surface of the dielectric layer that is adjacent to the upper electrode.

18. A method of manufacturing an integrated circuit device, comprising: forming an insulation layer that comprises oxygen on a substrate; and forming a first metal oxide layer on at least a portion of the insulation layer by exposing the at least a portion of the insulation layer to a first metal precursor that is reactive with the oxygen in the insulation layer.

19. The method of Claim 18, further comprising: forming a lower electrode on the substrate; and

forming an upper electrode on the insulation layer;

wherein forming the insulation layer that comprises oxygen on the substrate comprises:

forming the insulation layer that comprises oxygen on the lower electrode.

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20. The method of Claim 19, further comprising:

forming a second metal oxide layer on the substrate that encapsulates the lower electrode, the insulation layer, the first metal oxide layer, and the upper electrode.

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21. The method of Claim 20, wherein forming the first metal oxide layer comprises:

pulsing the first metal precursor over the integrated circuit device; and exposing the integrated circuit device/to an inert gas.

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22. The method of Claim 21, wherein forming the second metal oxide layer comprises:

pulsing a second metal precursor over the integrated circuit device; exposing the integrated circuit device to an inert gas; then pulsing oxygen gas over the integrated circuit device; then exposing the integrated circuit device to an inert gas.

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23. The method of $\not C$ laim 18, further comprising:

thermally treating the integrated circuit device in an oxygen atmosphere using one of a rapid thermal processing apparatus and a furnace type thermal processing apparatus.

24. The method of Claim 18, further comprising:

forming a conductive region on the substrate, the insulation layer being disposed on the conductive region and the substrate;

forming an opening in the insulation layer so as to expose at least a portion of the conductive region; and

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forming the first metal oxide layer on the at least a portion of the insulation layer while maintaining the exposed portion of the conductive region substantially devoid of the first metal oxide layer by exposing the at least a portion of the insulation layer and the exposed portion of the conductive region to the first metal precursor that is reactive with the oxygen in the insulation layer